

Docket No.: P2001,0011

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alfred Kersch
Applic. No. : 10/047,814
Filed : January 15, 2002
Title : Reaction Chamber for Processing a Substrate Wafer, and
Method for Operating the Chamber

ASSOCIATE POWER OF ATTORNEY

Hon. Commissioner of Patents and Trademarks,
Washington, D.C. 20231

Sir:

Please recognize MARKUS NOLFF (Reg. No. 37,006) as my associate in the matter in the above-identified application, with full powers. Please continue addressing all communications to the following address:

Lerner and Greenberg, P.A.
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Respectfully submitted,


For Applicant

Date: April 8, 2003

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